

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:	)	
Koichiro <b>TANAKA</b>	)	Confirmation No. 9528
Application No. 10/769,820	)	Examiner: Samuel M. Heinrich
Filed: February 3, 2004	)	Group Art Unit: 3742
For: LASER IRRADIATION STAGE, LASER	)	January 27, 2009
IRRADIATION OPTICAL SYSTEM, LASER	)	
IRRADIATION APPARATUS, LASER	)	
IRRADIATION METHOD, AND METHOD OF	)	
MANUFACTURING A SEMICONDUCTOR	)	
DEVICE	)	

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT UNDER 37 C.F.R. § 1.111**

In response to the Final Office Action mailed October 28, 2008, please amend the above-captioned application, as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks** follow the amendment section of this paper.